

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Ravi Iyer

Serial No.: 09/059,865

Filed: April 14, 1998

For: PLANARIZATION USING PLASMA
OXIDIZED AMORPHOUS SILICON

Group Art Unit: 2813

Examiner: Nguyen, T.

Atty Docket: MICS:0015--2/FLE
93-118.02

Assistant Commissioner
for Patents
Washington, D.C. 20231

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37 C.F.R. 1.8

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December 3, 1998

Date

Michael G. Fletcher

Sir:

AMENDMENT

In response to the Official Action mailed on August 3, 1998, please amend the above-referenced application as follows:

IN THE CLAIMS

Please cancel claim 1 without prejudice.

Please amend claims 18, 22, and 23 as set forth below:

18 (once amended). A method of manufacturing an integrated circuit, the method

comprising the steps of:

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